

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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| Applicant: | Wayne G. Renken | | |
| Title: | Process Condition Sensing Wafer and Data Analysis System | | |
| Application No.: | 10/685,550 | Filing Date: | October 14, 2003 |
| Examiner: | Samir M. Shah | Group Art Unit: | 2856 |
| Docket No.: | SENS.005US1 | Conf. No.: | 4924 |

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

RESPONSE TO OFFICE ACTION AND AMENDMENT

Sir:

This is in response to the non-final Office Action dated September 25, 2006, setting a shortened statutory period for response to expire December 25, 2006.

Claim Amendments are reflected in the listing of claims, which begins on page 2 of this paper.

Remarks begin on page 5 of this paper.

Reconsideration is kindly requested in light of the following remarks.